# Monthly LabAdviser update: 18/11 2016

|  |  |  |
| --- | --- | --- |
| Updated Subject | Contributor | Link to the updated pages |
| Ellipsometer   * Dielectric function determination of new thin-film semiconductors   + Learning about their electronic properties * Phase analysis of ”non-ideal” thin films * Thickness mapping (for its own sake and for resistivity mapping) * All-optical determination of electrical properties of transparent conductive materials | **Andrea Crovetto @nanotech** | <http://labadviser.danchip.dtu.dk/index.php?title=Specific_Process_Knowledge/Characterization/Optical_characterization/advanced_ellipsometry&oldid=24964>" |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

|  |
| --- |
|  |

|  |
| --- |
|  |

|  |  |  |
| --- | --- | --- |
| |  | | --- | |  |  |  | | --- | |  | |
|  |
|  |
|  |
|  |

|  |
| --- |
|  |
|  |

|  |
| --- |
| **APV and manual for fume hoods in D3 cleanroom** |
| **APV and manual for fumehoods in B-1. F-3 and C-1** |
| **Manual for LPCVD nitride furnace (6") E3** |
| **Manual for LPCVD TEOS furnace** | |
| **Manual for RIE2** | |
| **Manual for 7up-wafer C-1** | |
| **Manual for Anneal Bond furnace (C3)** | |
| **Manual for Gate Oxide furnace (A2)** | |
| **Manual for Furnace: Multipurpose Annealing** | |
| **Manual for SEM Supra 1** | |

|  |
| --- |
|  |